## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1762

Stouffer, Kelly M.

) Confirmation No. 7281

) Examiner:

y bento	Applica	nt: YOUNG HOON PARK, ET AL.
	Serial No.: 10/716,950	
	Filed:	November 19, 2003
	For:	METHOD OF DEPOSITING THIN FILM USING ALUMINUM OXIDE

## RESPONSE TO FINAL OFFICE ACTION

Mail Stop AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Applicants respectfully request entry of the following amendment and remarks contained herein in response to the Final Office Action mailed December 12, 2006. Applicants respectfully submit that the remarks contained herein place the instant application in condition for allowance.

Remarks begin on page 2 of this paper.